

(19)



JAPANESE PATENT OFFICE

PATENT ABSTRACTS OF JAPAN

(11) Publication number: **05133726 A**

(43) Date of publication of application: 28 . 05 . 93

(51) Int. Cl.

G01B 11/24**G01R 31/26****H01L 21/02****H01L 21/66**(21) Application number: **03325205**

(22) Date of filing: 13 . 11 . 91

(71) Applicant: **HITACHI LTD**

(72) Inventor:
MIYAZAKI ISAO
HAMADA MASAOMI
MATSUOKA KAZUHIKO
YAJIMA MINORU
NAGAI HARUO
AKAWA MASAYASU

(54) METHOD AND DEVICE FOR READING PATTERN**(57) Abstract:**

PURPOSE: To read patterns with a pattern reading method properly at all times by appropriately selecting the wave-length of irradiation light, and enhancing the pattern reading accuracy.

CONSTITUTION: A wafer 1 discharged from a loader/unloader 13 is transported to a pre-alignment device 17 by a robot 21. In the device 17, the wafer 1 is put in a specified attitude with its orientation flat 3 being brought into contact with a straight portion 19. The wafer 1 is transported by the robot 21 to a reading stage 31 of an artificial visual sensing device 30 and transferred onto the stage 31 while put in the preset attitude. The wafer 1 is supported horizontally by the stage 31 and positioned optically by an optical device 34 as confronting a TV camera 35 and illumination device 33 of the vision device 30. Then the device 30 executes reading of pellet ID code 9.

COPYRIGHT: (C)1993,JPO&Japio

